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U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
		2735/PDC/JB	09/111,454
LIST OF RELEVANT ART CITED BY APPLICANT		Applicant	
(Use several sheets if necessary)		Ben-Porath et al	
		Filing Date	Group
		July 8, 1998	2723

U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

VB	AR	"Electron Beam Pattern Inspection System Using Digital Image Processing."; Saitoh et al; J. Vac. Sci Technol B. Vol 4, No. 3 May/June 1986 - Pages 686-691
VB	AS	"Inspection For Defects of A Mask Containing One- to Submicrometer Patterns Using a Scanning Electron Microscope and Feature Extraction Method"; Y. Goto, et al; J. Vac. Sci. Technol 15 (3)0 May/June 1976; Pages 953-956
VB	AT	"Studies on an Electron-Beam Mask-defect Inspection System"; Y. Wada et al; J. Vac Sci Technol Vol 19 No. 1 May/June 1981

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10/2/98

INFORMATION DISCLOSURE CITATION IN AN APPLICATION						ATTY. DOCKET NO. 49959-013		SERIAL NO. 09/111,454	
						APPLICANT Ariel Ben-Porath			
(PTO-1449)						FILING DATE July 8, 1998		GROUP 2721 2723	
U.S. PATENT DOCUMENTS									
EXAMINER'S INITIALS		PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE		
VB		5,644,132	7/1/97	Litman et al.					
VB		5,699,447	12/16/97	Alumot et al.					
VB		4,941,980	7/17/90	Halavee et al.					
VB		5,594,245	1/14/97	Todokoro et al.					
VB		5,761,064	7/02/98	La et al.					
VB		5,412,210	5/2/95	Todokoro et al.					
FOREIGN PATENT DOCUMENTS									
EXAMINER'S INITIALS		PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation		
							Yes	No	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
EXAMINER		[Signature]			DATE CONSIDERED				
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Porath, et al

Filing Date

Group

July 8, 1998

2723

U.S. Patent Document

*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
VB	AA 5,862,055	1/19/99	Chen et al			RECEIVED
	AB					MAR 16 1999
	AC					Group 2700
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	
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09/111,454

FILING DATE
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GROUP
2721 2723

(PTO-1449)

U.S. PATENT DOCUMENTS

A circular ink stamp from the U.S. Patent & Trademark Office. The outer ring contains the text "U.S. PATENT & TRADEMARK OFFICE". In the center, the date "OCT 10 1999" is stamped. The stamp is partially obscured by a grid pattern.

FOREIGN PATENT DOCUMENTS

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